

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	1	("5346518").PN.	US-PGPUB; USPAT	OR	OFF	2006/01/09 14:39
L2	326	156/345.31.cds.	US-PGPUB; USPAT; USOCR	OR	ON	2006/01/09 14:53
L3	1820	((156/345.31) or (156/345.32) or (118/719)).CCLS.	US-PGPUB; USPAT	OR	OFF	2006/01/09 14:53
L4	618	3 and (pod "foup" cassette pod "smif")	US-PGPUB; USPAT	OR	ON	2006/01/09 14:54
L5	77	4 and ((hole orifice port) with (block\$3 obstruct\$3 cover\$3))	US-PGPUB; USPAT	OR	ON	2006/01/09 14:54
L6	21	3 and ((pod "foup" cassette pod "smif") same ((hole orifice port) with (block\$3 obstruct\$3 cover\$3)))	US-PGPUB; USPAT	OR	ON	2006/01/09 14:55
S7	66	(cassette pod "foup" "smif") same (hole with (cover\$3 obstruct\$4))	US-PGPUB; USPAT	OR	ON	2006/01/05 18:35
S8	935	(cassette pod "foup" "smif") same (hole with (cover\$3 obstruct\$4))	US-PGPUB; USPAT	OR	ON	2006/01/05 17:56
S9	131	(cassette pod "foup" "smif") same (hole with (cover\$3 obstruct\$4) same (arm robot hand))	US-PGPUB; USPAT	OR	ON	2006/01/05 17:57
S10	131	(cassette pod "foup" "smif") same (hole with (cover\$3 obstruct\$4) same (arm robot hand))	US-PGPUB; USPAT	OR	ON	2006/01/05 17:57
S11	68	((cassette pod "foup" "smif") with hole with (cover\$3 obstruct\$4) same (arm robot hand))	US-PGPUB; USPAT	OR	ON	2006/01/05 17:58
S12	10	((cassette pod "foup" "smif") with hole with (cover\$3 obstruct\$4) same (arm robot hand) same (wafer substrate semiconductor workpiece))	US-PGPUB; USPAT	OR	ON	2006/01/05 18:01
S13	4	((cassette pod "foup" "smif") with hole with (block\$4)) same (arm robot hand) same (wafer substrate semiconductor workpiece)	US-PGPUB; USPAT	OR	ON	2006/01/05 18:01
S14	6	((cassette pod "foup" "smif") with hole with (block\$4)) same (wafer substrate semiconductor workpiece)	US-PGPUB; USPAT	OR	ON	2006/01/05 18:01
S15	2	(cassette pod "foup" "smif") with hole with (block\$3 cover\$3 obstruct\$4) with (substrate wafer semiconductor workpiece)	US-PGPUB; USPAT	OR	ON	2006/01/05 18:03
S16	3	(cassette pod "foup" "smif") with hole with (block\$3 cover\$3 obstruct\$4) with (substrate wafer semiconductor workpiece)	EPO; JPO; DERWENT	OR	ON	2006/01/05 18:05
S17	11	(cassette pod "foup" "smif") same (hole opening orifice) same (block\$3 cover\$3 obstruct\$4) same (substrate wafer semiconductor workpiece) same (arm tool robot hand transfer\$4 transport\$4 convey\$4)	EPO; JPO; DERWENT	OR	ON	2006/01/05 18:07
S18	105	(cassette pod "foup" "smif") same (hole opening orifice) same (block\$3 cover\$3 obstruct\$4) same (substrate wafer semiconductor workpiece) same (arm tool robot hand transfer\$4 transport\$4 convey\$4)	US-PGPUB; USPAT; USOCR	OR	ON	2006/01/05 18:23
S19	330	((hole opening orifice) same (block\$3 cover\$3 obstruct\$4) same (arm tool robot hand transfer\$4 transport\$4 convey\$4)) and 414/935-941.cds.	US-PGPUB; USPAT; USOCR	OR	ON	2006/01/09 14:52
S20	64	(cassette same (hole opening orifice) same (block\$3 cover\$3 obstruct\$4) same (arm tool robot hand transfer\$4 transport\$4 convey\$4)) and 414/935-941.cds.	US-PGPUB; USPAT; USOCR	OR	ON	2006/01/05 18:24
S21	81	((cassette pod "foup") same (hole opening orifice) same (block\$3 cover\$3 obstruct\$4) same (arm tool robot hand transfer\$4 transport\$4 convey\$4)) and 414/935-941.cds.	US-PGPUB; USPAT; USOCR	OR	ON	2006/01/05 18:25
S22	21	((cassette pod "foup") with (hole opening orifice) with (block\$3 cover\$3 obstruct\$4) with (arm tool robot hand transfer\$4 transport\$4 convey\$4)) and 414/935-941.cds.	US-PGPUB; USPAT; USOCR	OR	ON	2006/01/05 18:28

S23	385	((cassette pod "foup") with (hole opening orifice) with (block\$3 cover\$3 obstruct\$4) with (arm tool robot hand transfer\$4 transport\$4 convey\$4))	US-PGPUB; USPAT; USOCR	OR	ON	2006/01/05 18:28
S24	65	((cassette pod "foup") with (hole opening orifice) with (block\$3 cover\$3 obstruct\$4) with (arm tool robot hand transfer\$4 transport\$4 convey\$4) with (bottom lower))	US-PGPUB; USPAT; USOCR	OR	ON	2006/01/05 18:29
S25	74	((cassette pod "foup") with (hole opening orifice) with (block\$3 cover\$3 obstruct\$4) with (arm tool robot hand transfer\$4 transport\$4 convey\$4) with (bottom lower base))	US-PGPUB; USPAT; USOCR	OR	ON	2006/01/05 18:29
S26	41	((cassette pod "foup") with (hole opening orifice) with (block\$3 cover\$3 obstruct\$4) with (arm tool robot hand transfer\$4 transport\$4 convey\$4) with (bottom lower base) with (side\$1wall wall side))	US-PGPUB; USPAT; USOCR	OR	ON	2006/01/05 18:30
S27	1	jiang-i-tiang.in. peng-yu-ling.in. cheng-kuo-shun.in.	US-PGPUB; USPAT; USOCR	OR	ON	2006/01/05 18:31
S28	0	jiang-i-tiang.in. peng-yu-ling.in. cheng-kuo-shun.in.	EPO; JPO; DERWENT	OR	ON	2006/01/05 18:32
S29	2833	au.as. optronics.as.	EPO; JPO; DERWENT	OR	ON	2006/01/05 18:32
S30	4	S29 and (cassette pod "foup")	EPO; JPO; DERWENT	OR	ON	2006/01/05 18:34
S31	4	S29 and (cassette pod "foup" "smif")	EPO; JPO; DERWENT	OR	ON	2006/01/05 18:34
S32	437	(cassette pod "foup" "smif") with (hole opening orifice) with (wall side\$1wall side)	US-PGPUB; USPAT	OR	ON	2006/01/05 18:36
S33	3273558	(cassette pod "foup" "smif") with (hole opening orifice) with (wall side\$1wall side) iwith (bottom lower)	US-PGPUB; USPAT	OR	ON	2006/01/05 18:37
S34	105	(cassette pod "foup" "smif") with (hole opening orifice) with (wall side\$1wall side) with (bottom lower)	US-PGPUB; USPAT	OR	ON	2006/01/05 18:37
S35	1	(cassette pod "foup" "smif") with (hole opening orifice) with (wall side\$1wall side) with (bottom lower) with (block\$3 obstruct\$3 cover\$3) with (prohibit\$3 prevent\$3)	US-PGPUB; USPAT	OR	ON	2006/01/05 18:38
S36	4	(cassette pod "foup" "smif") with (hole opening orifice) with (wall side\$1wall side) with (block\$3 obstruct\$3 cover\$3) with (prohibit\$3 prevent\$3)	US-PGPUB; USPAT	OR	ON	2006/01/05 18:39
S37	47	(cassette pod "foup" "smif") with (hole opening orifice) with (wall side\$1wall side) with (block\$3 obstruct\$3 cover\$3)	US-PGPUB; USPAT	OR	ON	2006/01/05 18:42
S38	10	(cassette pod "foup" "smif") with (hole opening orifice) with (wall side\$1wall side) with (block\$3 obstruct\$3 cover\$3)	EPO; JPO; DERWENT	OR	ON	2006/01/05 18:42
S39	272	(206/710).CCLS.	US-PGPUB; USPAT	OR	OFF	2006/01/06 12:03
S40	5	("4129211" "4668484" "5377476" "5713711" "5810537").PN.	US-PGPUB; USPAT; USOCR	OR	ON	2006/01/06 14:12
S41	1	("6540467").URPN.	USPAT	OR	ON	2006/01/06 16:19
S42	480	((414/266) or (414/267) or (220/661)).CCLS.	US-PGPUB; USPAT	OR	OFF	2006/01/06 16:19
S43	189963	((wall with side) (side\$1wall)) with (hole orifice cut\$1out opening)	US-PGPUB; USPAT	OR	ON	2006/01/06 16:23
S44	55	S42 and S43	US-PGPUB; USPAT	OR	ON	2006/01/06 16:21
S45	1	S42 and S43 and (substrate wafer semiconductor workpiece)	US-PGPUB; USPAT	OR	ON	2006/01/06 16:21
S46	30925	(((wall with side) (side\$1wall)) with (hole orifice cut\$1out opening)) and (substrate wafer semiconductor workpiece)	US-PGPUB; USPAT	OR	ON	2006/01/06 16:23

S47	13	((wall with side) (side\$1wall)) with (hole orifice cut\$1out opening) with (obstruct\$4 cover\$4 clos\$4 block\$4) with (prevent\$4 prohibit\$4) with (damag\$3)) and (substrate wafer semiconductor workpiece)	US-PGPUB; USPAT	OR	ON	2006/01/06 16:26
S48	42	((wall side side\$1wall) with (hole orifice cut\$1out opening) with (obstruct\$4 cover\$4 clos\$4 block\$4) with (prevent\$4 prohibit\$4) with (damag\$3)) and (substrate wafer semiconductor workpiece)	US-PGPUB; USPAT	OR	ON	2006/01/06 16:26
S49	0	((wall side side\$1wall) with (hole orifice cut\$1out opening) with (obstruct\$4 cover\$4 clos\$4 block\$4) with (prevent\$4 prohibit\$4) with (damag\$3)) and ((substrate wafer semiconductor workpiece) same (cassette pod container "foup" "smif"))	US-PGPUB; USPAT	OR	ON	2006/01/06 16:27
S50	11	((wall side side\$1wall) with (hole orifice cut\$1out opening) with (prevent\$4 prohibit\$4) with (damag\$3)) and ((substrate wafer semiconductor workpiece) same (cassette pod container "foup" "smif"))	US-PGPUB; USPAT	OR	ON	2006/01/06 16:46
S51	17	((hole orifice cut\$1out opening) with (prevent\$4 prohibit\$4) with (damag\$3) with (substrate wafer semiconductor workpiece)) same (cassette pod container "foup" "smif")	US-PGPUB; USPAT	OR	ON	2006/01/06 16:52
S52	9	((hole orifice cut\$1out opening) with (prevent\$4 prohibit\$4) with (damag\$3) with (substrate wafer semiconductor workpiece)) same (cassette pod container "foup" "smif")	EPO; JPO; DERWENT	OR	ON	2006/01/06 16:48
S53	13	((hole orifice cut\$1out opening) with (prevent\$4 prohibit\$4) with (damag\$3) with (substrate wafer semiconductor workpiece)) and (cassette pod container "foup" "smif")	EPO; JPO; DERWENT	OR	ON	2006/01/06 16:48
S54	10	("3682083" "3877134" "4153164" "4176751" "4493418" "4600231" "4724963" "5308993" "5351836" "5364144").PN.	US-PGPUB; USPAT; USOCR	OR	ON	2006/01/06 17:11
S55	9	("5638958").URPN.	USPAT	OR	ON	2006/01/06 17:25